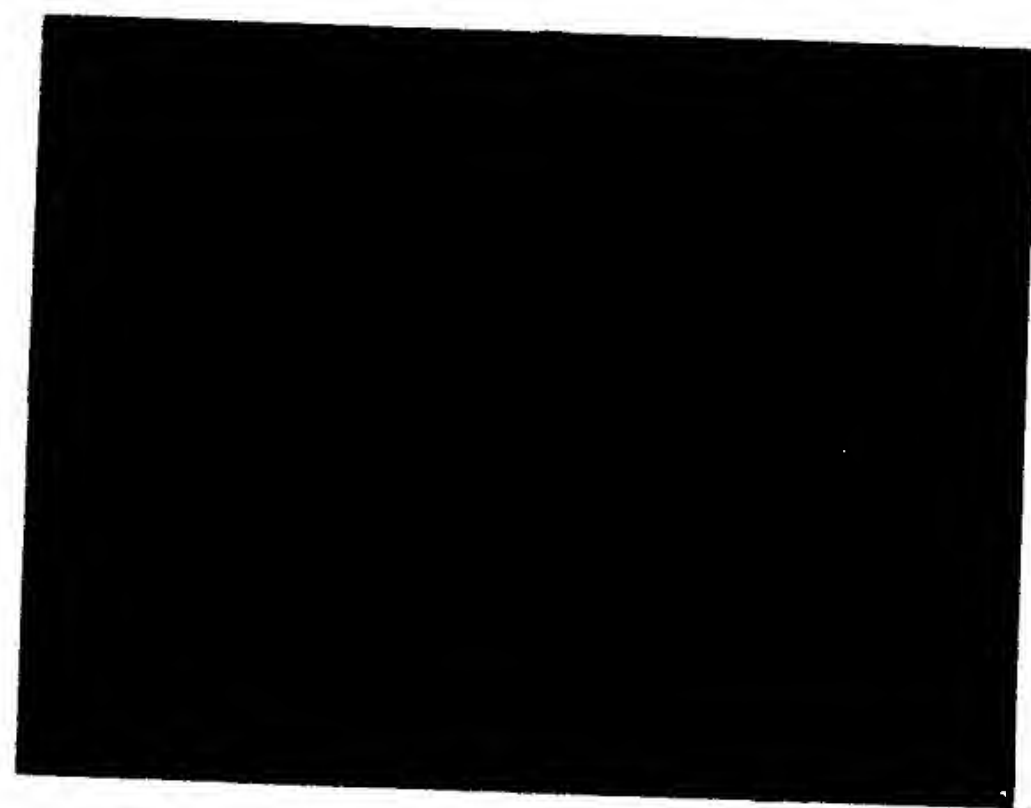


*Fig. 1*



TRENCH

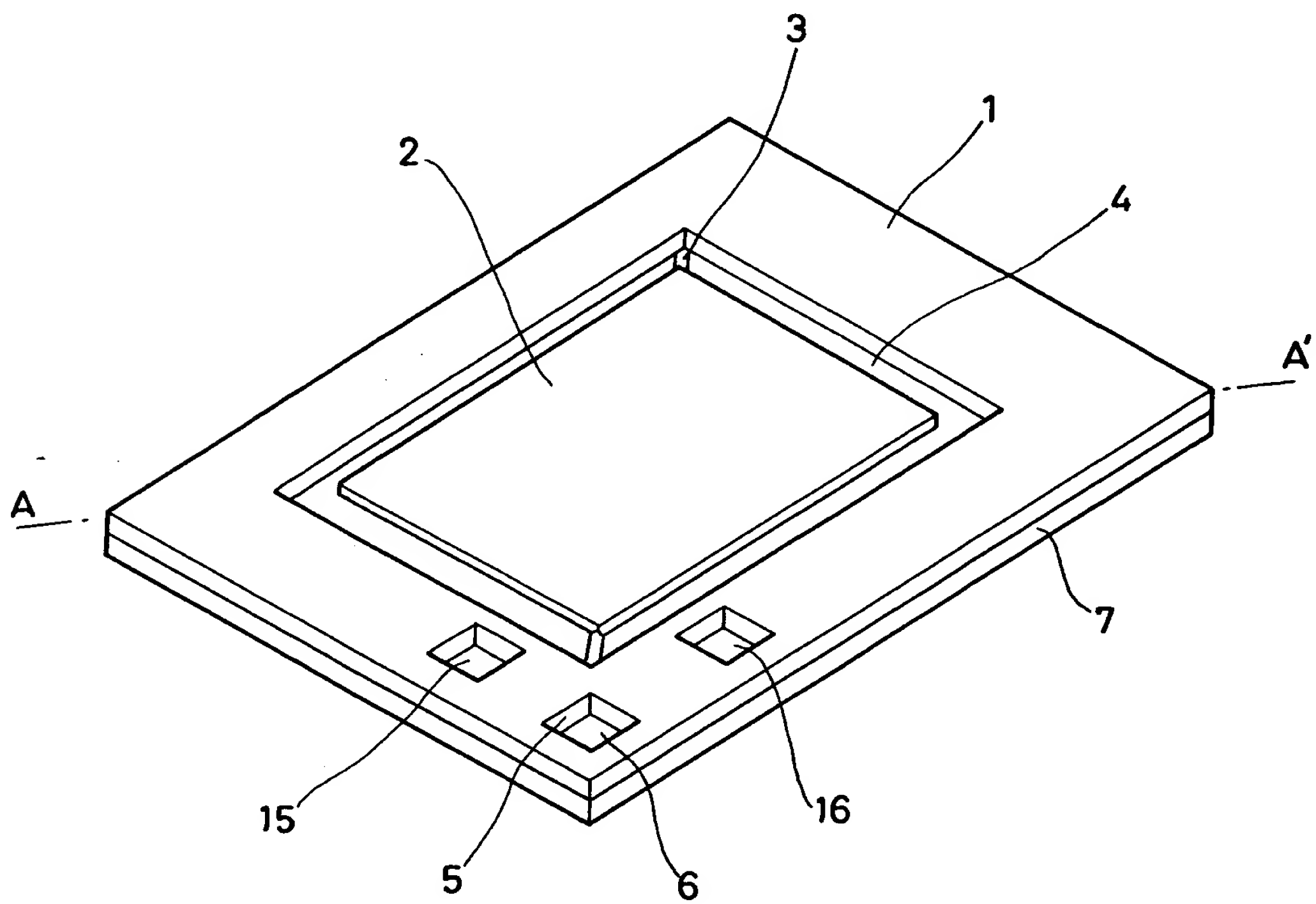
*Fig. 2*



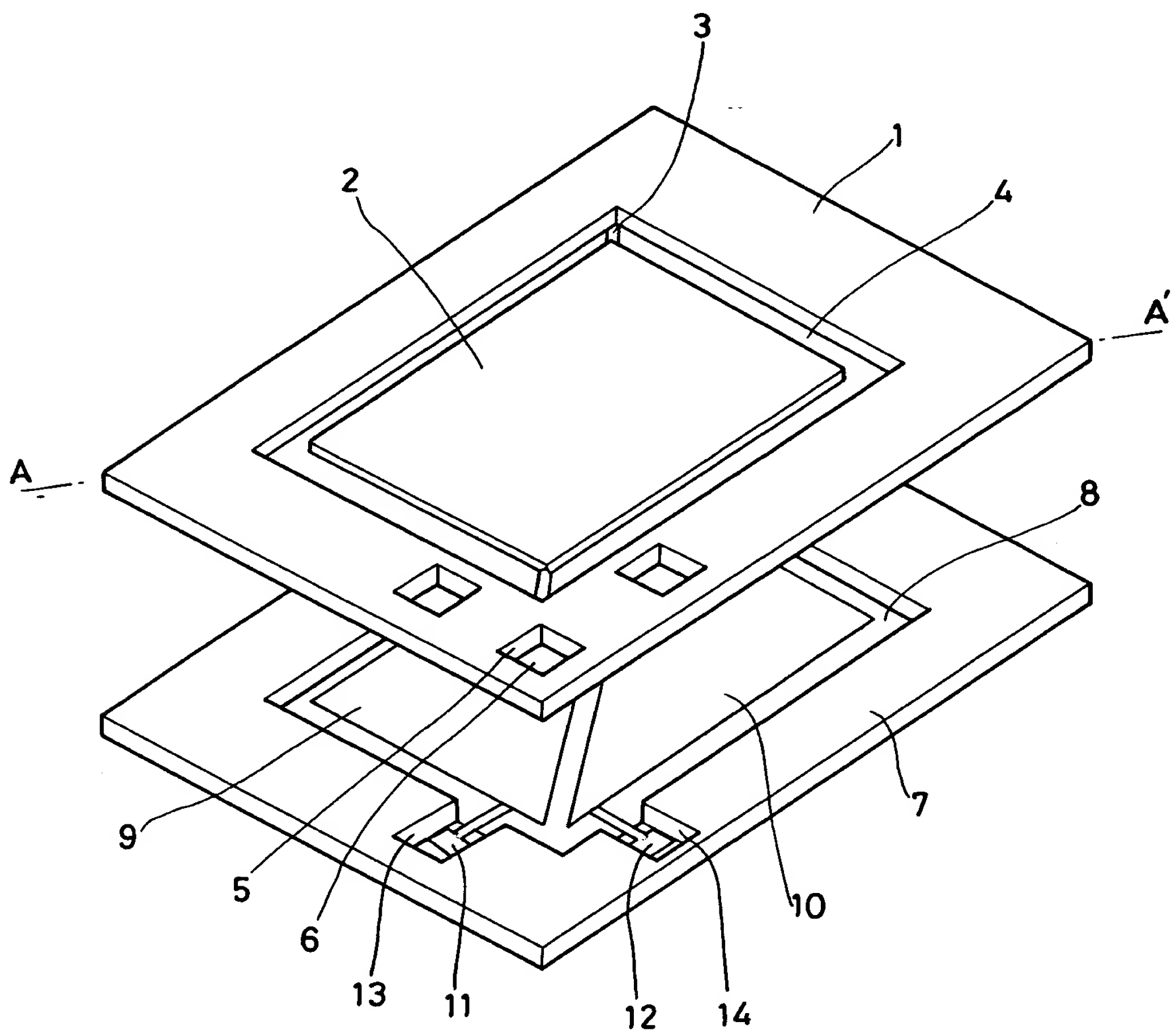
TRENCH

AI FILM

*Fig. 3*



*Fig. 4*

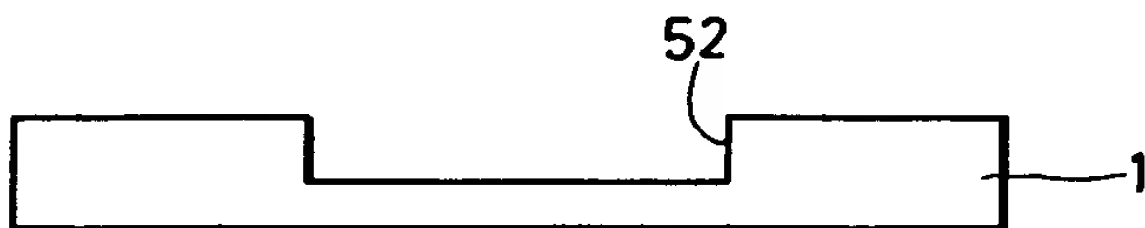


A ————— A'

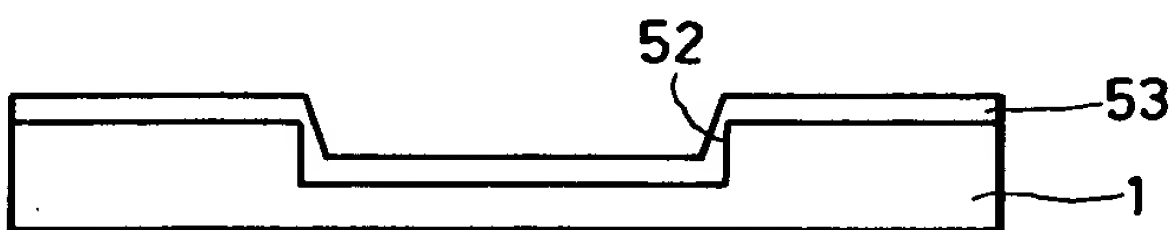
**Fig. 5A**



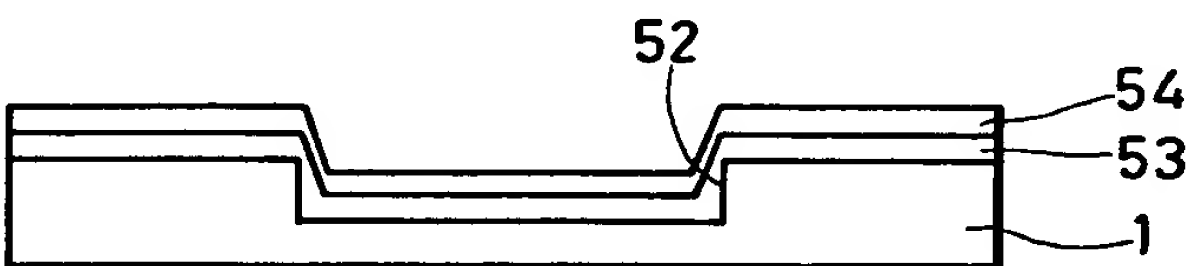
**Fig. 5B**



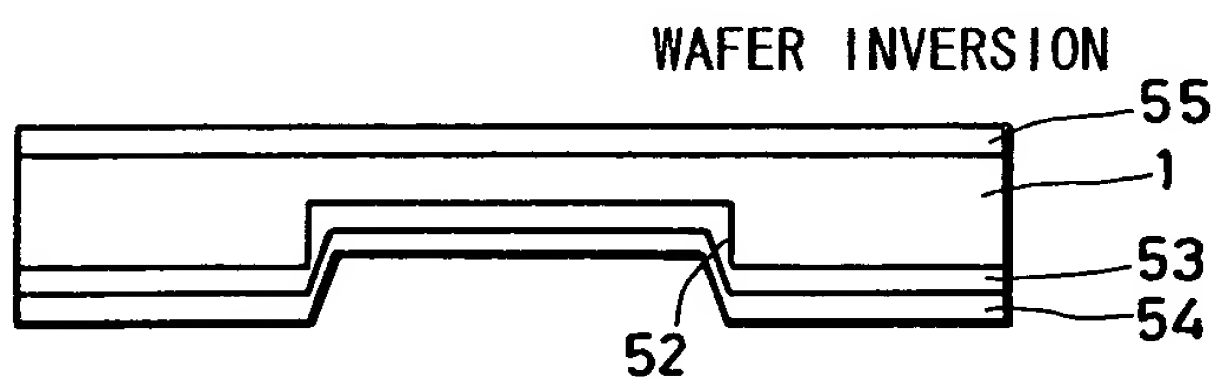
**Fig. 5C**



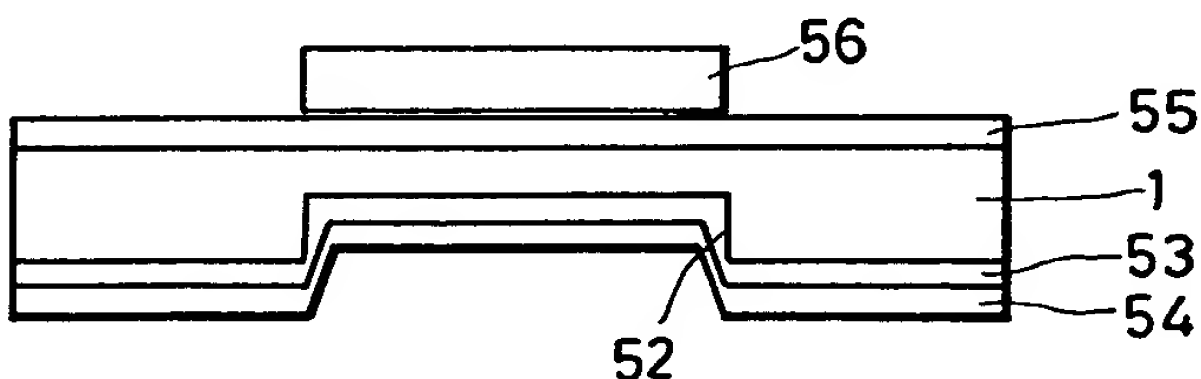
**Fig. 5D**



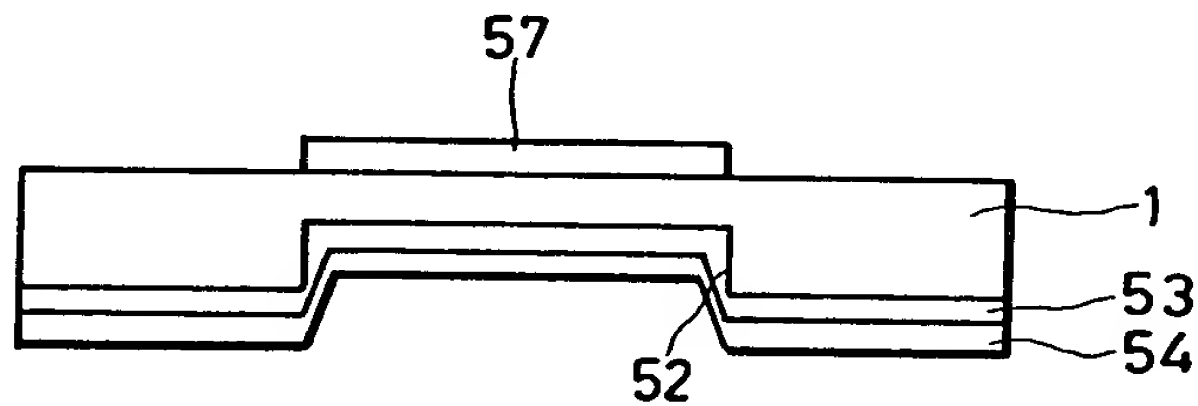
**Fig. 5E**



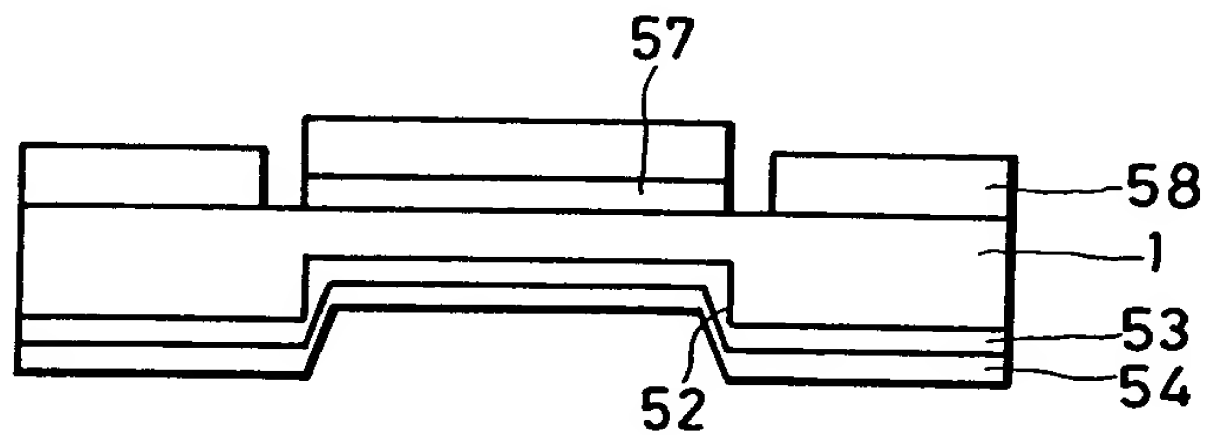
**Fig. 5F**



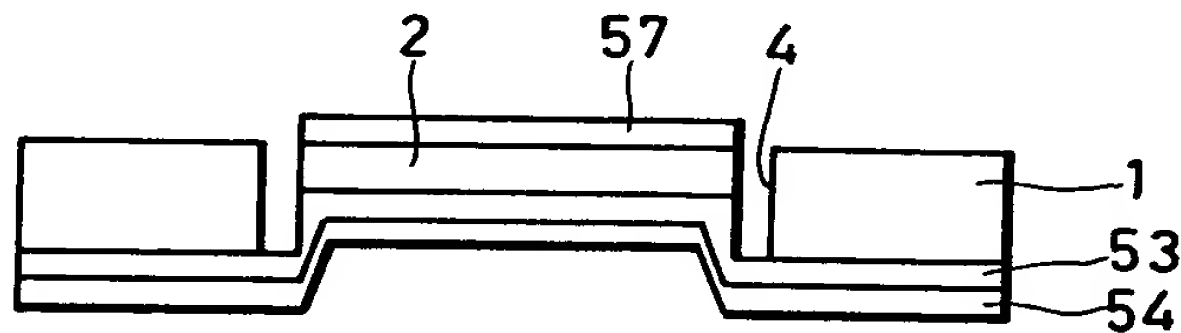
**Fig. 6A**



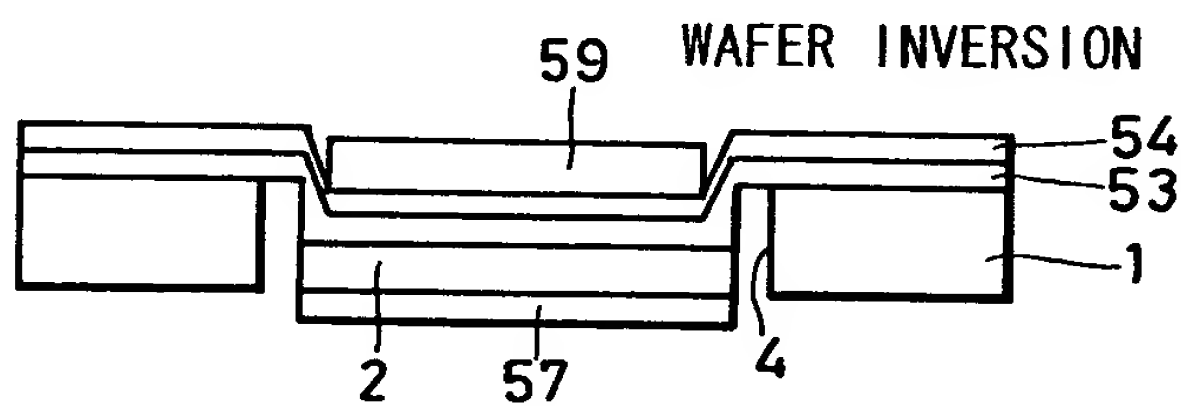
**Fig. 6B**



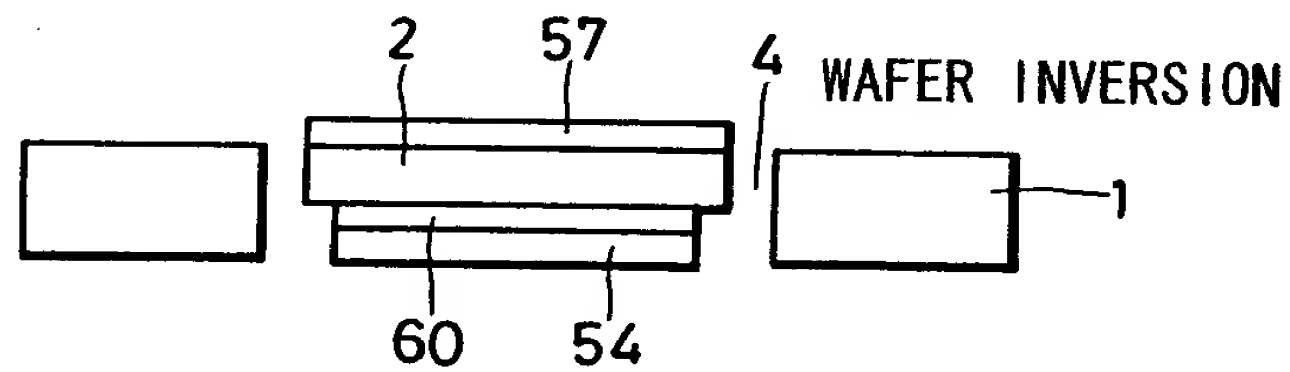
**Fig. 6C**



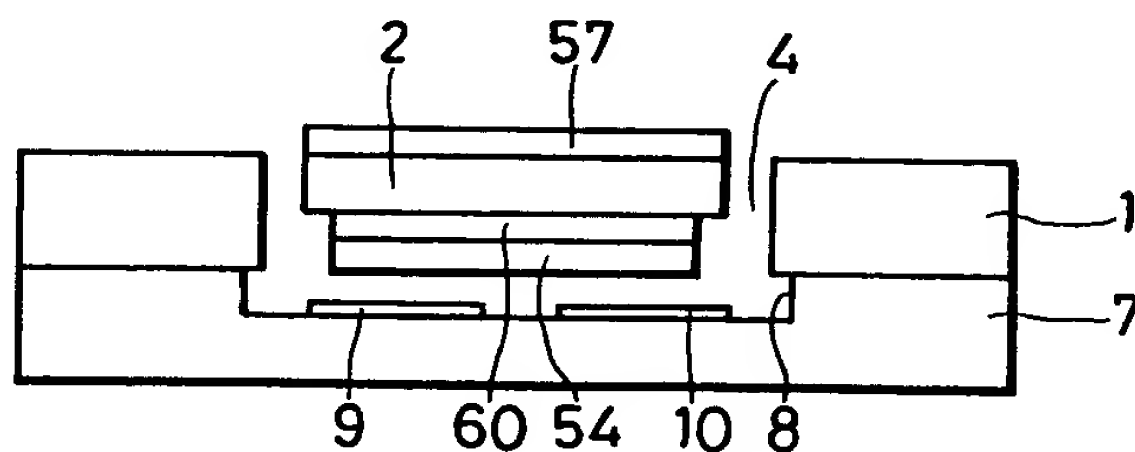
**Fig. 6D**



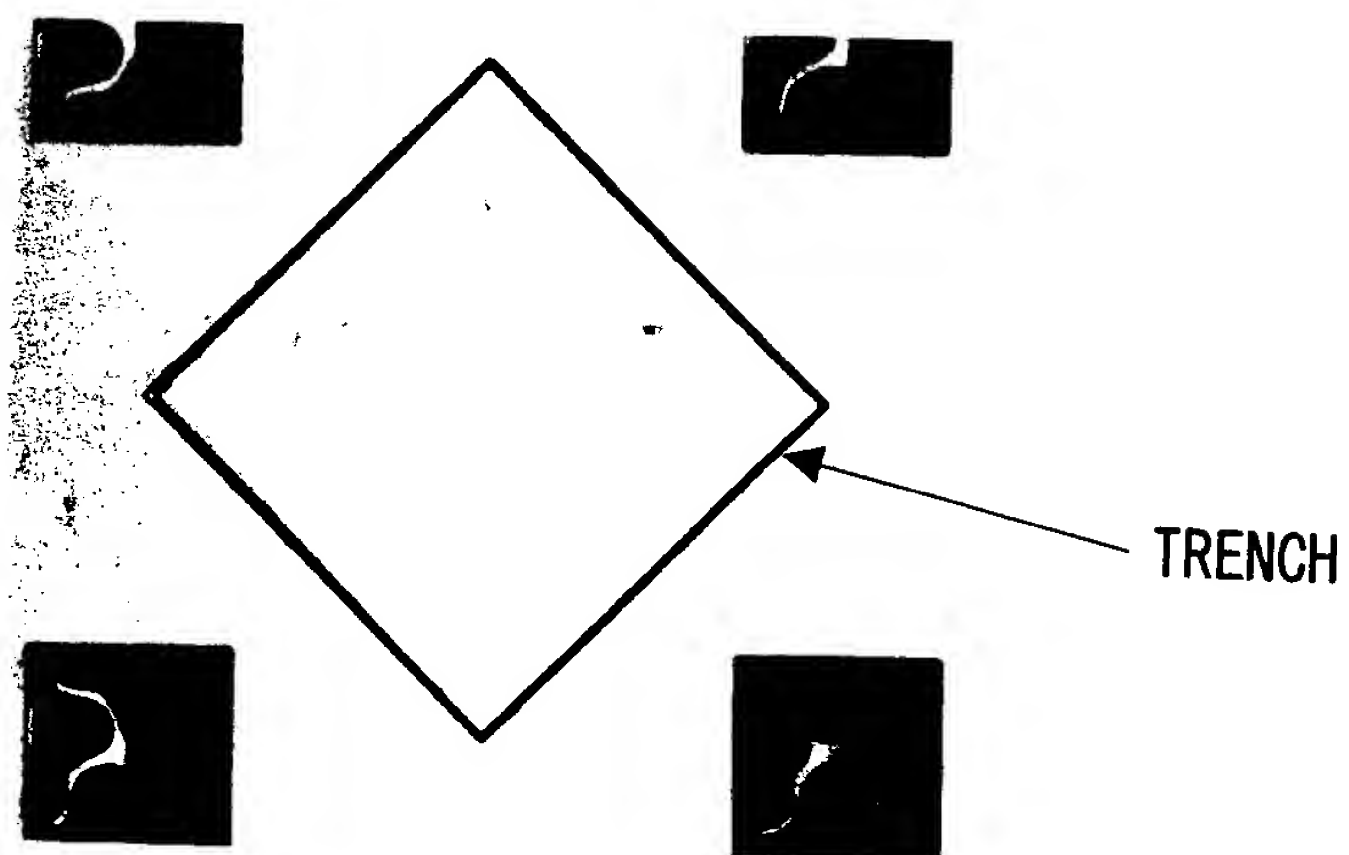
**Fig. 6E**



**Fig. 6F**



*Fig. 7*



*Fig. 8*

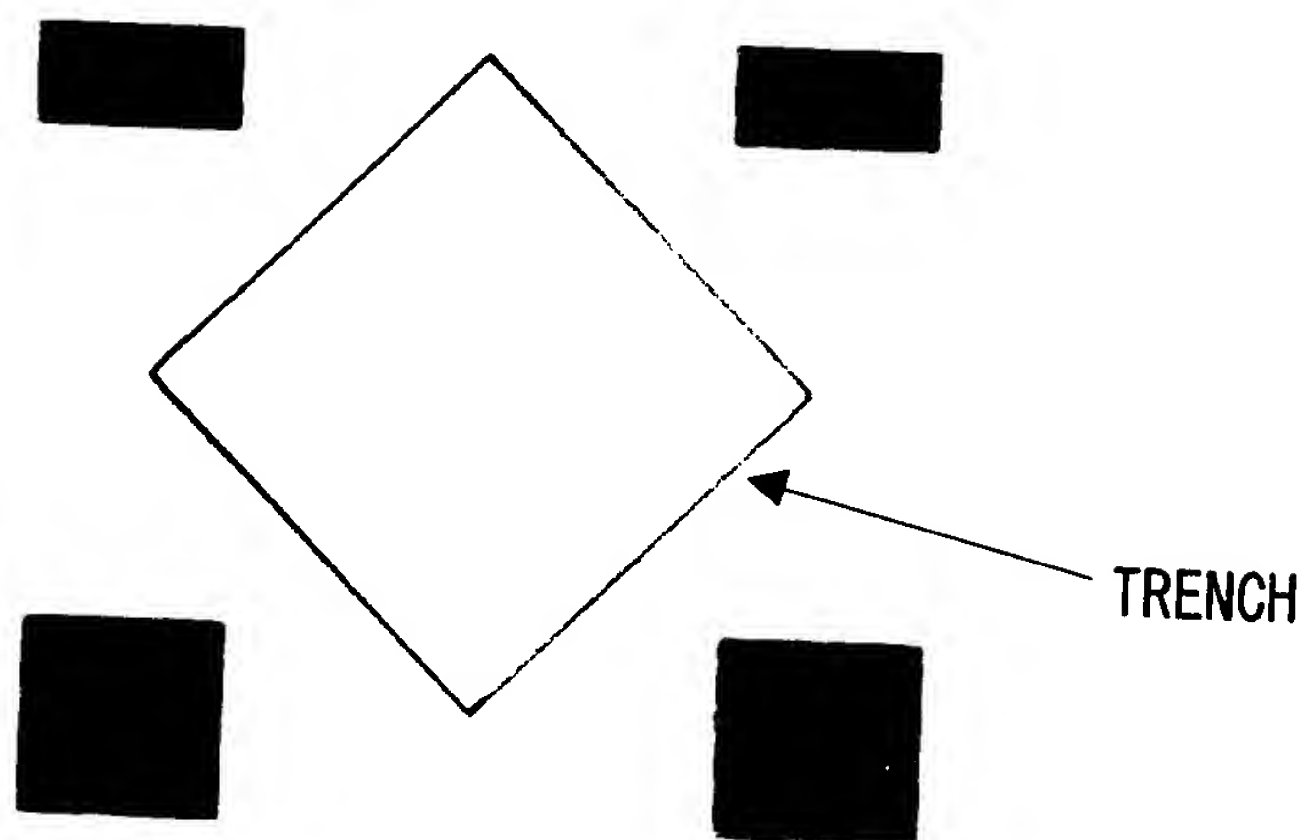
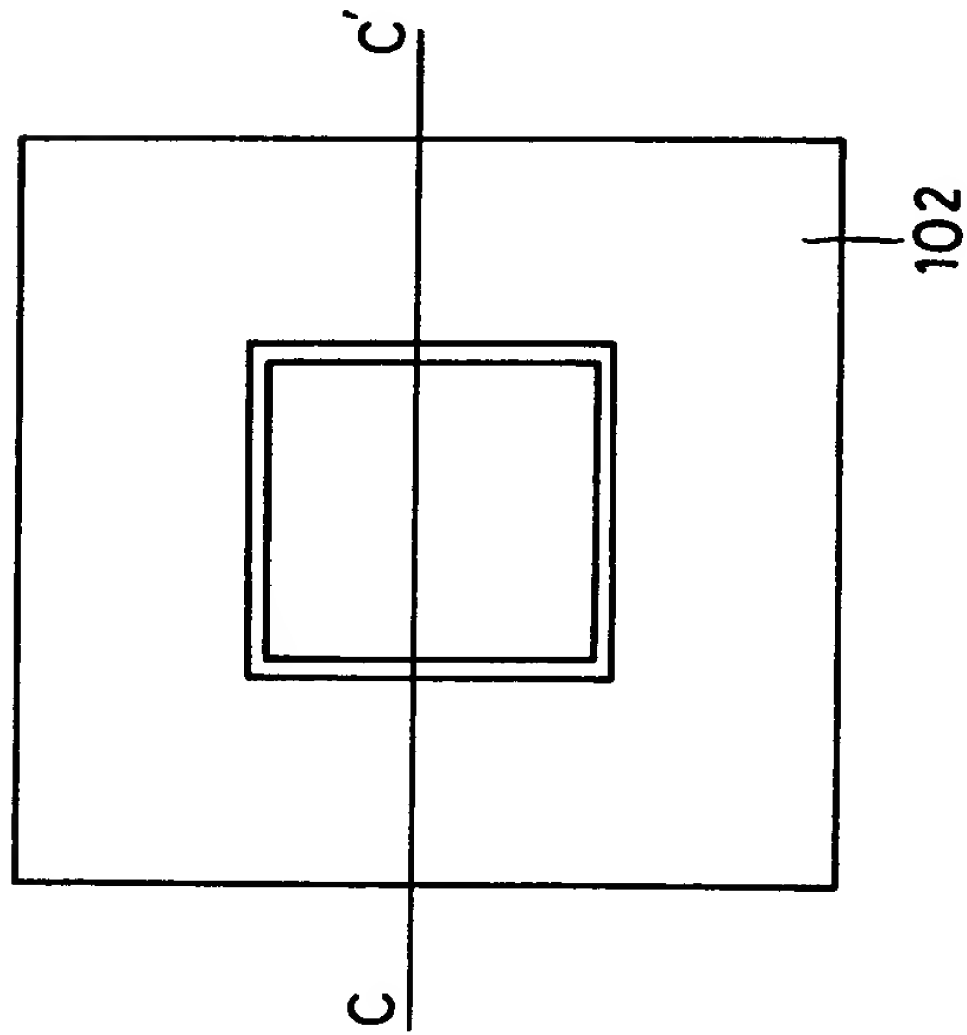
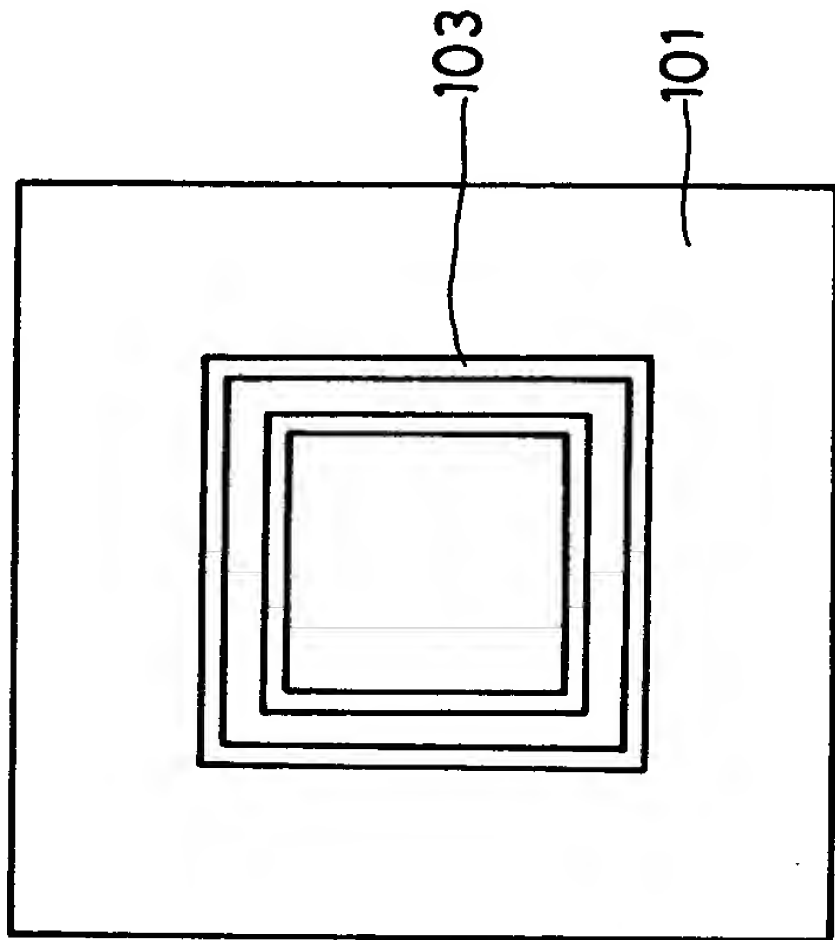


Fig. 9A



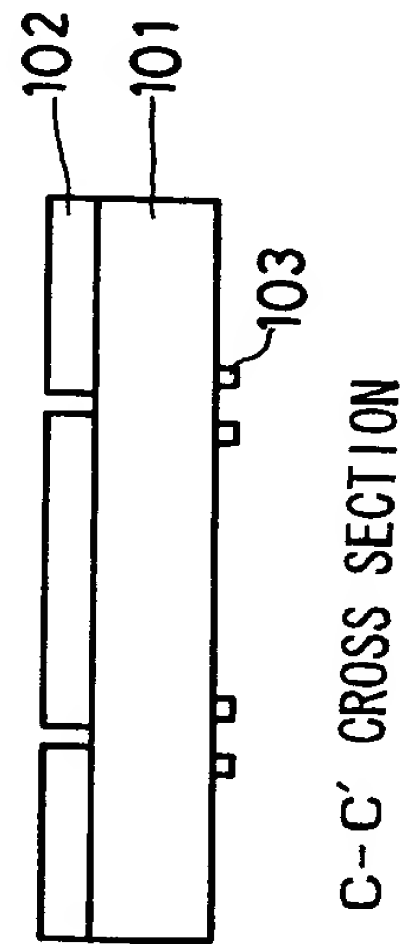
TOP SURFACE OF Si SUBSTRATE

Fig. 9B



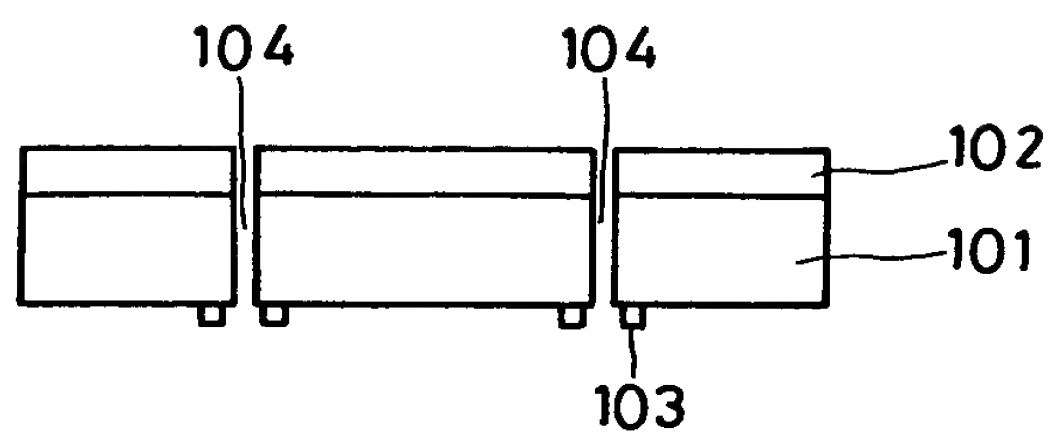
BACK SURFACE OF Si SUBSTRATE

Fig. 9C



C-C' CROSS SECTION

*Fig. 10*



*Fig. 11*

